

Title (en)

Protective device for electrode holders in CVD reactors

Title (de)

Schutzvorrichtung für Elektrodenhalterungen in CVD Reaktoren

Title (fr)

Dispositif de protection de supports d'électrodes dans des réacteurs CVD

Publication

EP 2544215 A3 20130220 (DE)

Application

EP 12173737 A 20120627

Priority

DE 102011078727 A 20110706

Abstract (en)

[origin: EP2544215A2] The device comprises an electrode for accommodating a filament rod on an electrode holder (21), which includes an electrically conductive material and is installed in a recess of a bottom plate (11). An intermediate space between the electrode holder and the bottom plate is sealed by a sealing material (41), which is protected by a protective body. The protective body is: made up of parts that are arranged concentrically around the electrode holder; and arranged in a ring-like manner around the electrode and the electrode holder. The device comprises an electrode for accommodating a filament rod on an electrode holder (21), which includes an electrically conductive material and is installed in a recess of a bottom plate (11). An intermediate space between the electrode holder and the bottom plate is sealed by a sealing material (41), which is protected by a protective body. The protective body is: made up of parts that are arranged concentrically around the electrode holder; and arranged in a ring-like manner around the electrode and the electrode holder, where a height of the protective body increases in sections in the direction of the electrode holder. An independent claim is included for a process for producing polycrystalline silicon.

IPC 8 full level

H01J 37/32 (2006.01); **C01B 33/035** (2006.01)

CPC (source: EP KR US)

C01B 33/035 (2013.01 - EP KR US); **C23C 16/4401** (2013.01 - EP KR US); **C23C 16/46** (2013.01 - EP KR US);
H01J 37/32477 (2013.01 - EP KR US); **H01J 37/32559** (2013.01 - EP KR US)

Citation (search report)

- [X] US 2010147219 A1 20100617 - HSIEH JUI HAI [TW], et al
- [XPA] WO 2011092276 A1 20110804 - G & R TECHNOLOGY GROUP AG [DE], et al
- [A] DE 2432383 A1 19760122 - SIEMENS AG
- [A] EP 2161241 A2 20100310 - MITSUBISHI MATERIALS CORP [JP]

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WO2014146877A1; WO2014143910A1

Designated contracting state (EPC)

AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

Designated extension state (EPC)

BA ME

DOCDB simple family (publication)

EP 2544215 A2 20130109; EP 2544215 A3 20130220; EP 2544215 B1 20150520; CA 2779221 A1 20130106; CA 2779221 C 20141007;
CN 102864440 A 20130109; CN 102864440 B 20151118; DE 102011078727 A1 20130110; ES 2543887 T3 20150825;
JP 2013018701 A 20130131; JP 5670389 B2 20150218; KR 101600651 B1 20160307; KR 20130006350 A 20130116;
US 2013011581 A1 20130110

DOCDB simple family (application)

EP 12173737 A 20120627; CA 2779221 A 20120606; CN 201210232308 A 20120705; DE 102011078727 A 20110706;
ES 12173737 T 20120627; JP 2012151123 A 20120705; KR 20120073449 A 20120705; US 201213535844 A 20120628